

10/790,296H1907/AMDP986USAMENDMENTS TO THE CLAIMS

This listing of claims will replace all prior versions of claims in the application:

Listing of Claims:

1. (Currently amended) A system that facilitates measurement and correction of overlay between multiple layers of a wafer, comprising:
 - an overlay target that represents overlay between three or more layers of a wafer;
 - a measurement component that determines overlay error existent in the overlay target, and determines overlay error between the three or more layers of the wafer, where the measurement component comprises a comparison component that compares a captured signature with one or more stored signatures to facilitate determination of overlay error existent in the overlay target; and
 - a control component that utilizes the overlay error determined by the measurement component to correct overlay error between the three or more layers of the wafer, the control component facilitating concurrent overlay correction of two or more wafers.
2. (Canceled)
3. (Previously presented) The system of claim 1, the control component provides more correction in a first dimension and less correction in a second dimension in an instance in which design rule requirements tolerate less overlay error in the first dimension when compared to the second dimension.
4. (Previously presented) The system of claim 1, a substantial overlay correction between non-adjacent layers of the wafer in a first dimension correlates to a substantial overlay correction between adjacent layers of the wafer in a second dimension.
5. (Previously presented) The system of claim 1, an insubstantial overlay correction between non-adjacent layers of the wafer in a first dimension correlates to an insubstantial overlay correction between adjacent layers of the wafer in a second dimension.

10/790,296

H1907/AMDP986US

6. (Previously presented) The system of claim 1, the control component manipulates at least one of temperature(s) associated with a process step, pressure(s) associated with a process step, concentration of gas(es) within a process step, concentration of chemical(s) within a process step, composition of gas(es) within a process step, composition of chemical(s) within a process step, flow rate of gas(es) within a process step, flow rate of chemical(s) within a process step, timing parameters associated with a process step, and excitation of voltages associated with a process step.

7. (Previously presented) The system of claim 1, at least one of concentration, rate of flow, and degree of abrasiveness is controlled to correct overlay error.

8. (Previously presented) The system of claim 1, the control component facilitates correction of rotational overlay error.

9. (Previously presented) The system of claim 1, the measurement component and the control component are integrated with at least one process step to facilitate *in situ* correction of overlay error.

10. (Canceled)

11. (Previously presented) The system of claim 1, the overlay target has a structure of at least one of box-in-box, frame-in-frame, segmented frame, and periodic structure.

12. (Previously presented) The system of claim 1, the overlay target comprises one or more gratings.

10/790,296H1907/AMDP986US

13. (Previously presented) The system of claim 1, the measurement component comprising:
an optical microscope utilized to capture an image of the overlay target; and
a comparison component that compares the captured image with one or more stored
images, wherein the comparison facilitates determination of overlay error existent in the overlay
target.
14. (Previously presented) The system of claim 1, the measurement component further
comprising:
a light emitting component that delivers light incident to the overlay target; and
a light capturing component utilized to capture a signature that results from the incident
light contacting the overlay target.
15. (Previously presented) The system of claim 1, optical microscopy techniques are utilized
to facilitate measurement of overlay error existent in the overlay target.
16. (Previously presented) The system of claim 1, scatterometry techniques are utilized to
facilitate measurement of overlay error existent in the overlay target.
17. (Previously presented) The system of claim 1, scanning electron microscopy techniques
are utilized to facilitate measurement of overlay error existent in the overlay target.
18. (Previously presented) The system of claim 1, Fourier transform infrared scatterometry
techniques are utilized to facilitate measurement of overlay error existent in the overlay target.
19. (Original) A stand-alone metrology unit comprising the system of claim 1.
20. (Original) The system of claim 1, the overlay target associated with a particular die on the
wafer.

10/790,296H1907/AMDP986US

21. (Original) The system of claim 1, the wafer subdivided into a grid comprising a plurality of cells, wherein the grid facilitates measurement and recordation of overlay error at particular portions of the wafer.

22. (Previously presented) The system of claim 21, the wafer discarded if a threshold percentage of cells exhibit a threshold level of overlay error.

23. (Currently amended) A method for measuring and correcting overlay error in more than two layers of a wafer, the method comprising:

generating a multi-layered overlay target, wherein disparate layers of the overlay target represent disparate layers of the wafer;

delivering light incident to the overlay target;

capturing a signature that results from the incident light contacting the overlay target;

comparing the captured signature with one or more stored signatures to facilitate determination of overlay error existent in the overlay target;

approximating overlay error between layers on a wafer *via* measuring overlay error between representative layers of the overlay target; *[[and]]*

correcting overlay error between layers of a wafer based at least in part on the measured overlay error existent in the representative layers of the overlay target; *and*

facilitating concurrent overlay correction of two or more wafers based at least in part upon the measured overlay error.

24. (Previously presented) A stand-alone metrology unit utilizing the method of claim 23.

25. (Previously presented) The method of claim 23, the layers of the wafer are non-adjacent layers.

10/790,296H1907/AMDP986US

26. (Previously presented) The method of claim 23, the overlay error corrected via modifying one or more of temperature(s) associated with a process step, pressure(s) associated with a process step, concentration of gas(es) within a process step, concentration of chemical(s) within a process step, composition of gas(es) within a process step, composition of chemical(s) within a process step, flow rate of gas(es) within a process step, flow rate of chemical(s) within a process step, timing parameters associated with a process step, and excitation of voltages associated with a process step.
27. (Previously presented) The method of claim 23, the layers of the wafer are adjacent layers.
28. (Canceled)
29. (Previously presented) The method of claim 23 further comprising:
substantially correcting overlay error between non-adjacent layers of the wafer in a first dimension; and
substantially correcting overlay error between adjacent layers of the wafer in a second dimension.
30. (Previously presented) The method of claim 23, further comprising:
insubstantially correcting overlay error between non-adjacent layers of the wafer in a first dimension; and
insubstantially correcting overlay error between adjacent layers of the wafer in a second dimension.
31. (Previously presented) The method of claim 23, further comprising providing a greater amount of overlay correction in one particular direction in comparison to a substantially perpendicular dimension.
32. (Canceled)

10/790,296H1907/AMDP986US

33. (Currently Amended) A system that corrects overlay error between three or more layers of [[a]] at least one wafer, comprising:

means for creating an overlay target, the overlay target representing three or more layers of a wafer;

means for delivering light incident to the overlay target;

means for capturing a signature that results from the light incident to the overlay target;

means for comparing the captured signature with one or more stored signatures to determine overlay error in the overlay target; and

means for concurrently correcting overlay error between non-adjacent layers of the at least one wafer based at least in part on the measurements relating to the overlay target.

34. (Currently Amended) A system for correcting overlay error between three or more layers of [[a]] at least one wafer, where the system comprises:

a measurement component that comprises:

a light emitting component that delivers light incident to the overlay target;

a light capturing component utilized to capture a signature that results from the incident light contacting the overlay target; and

a comparison component that compares a captured signature with one or more stored signatures to determine overlay error associated with the overlay target; and

a receiving component that receives measurements associated with overlay error between three or more layers of the wafer; and

a control component that effectuates a particular concurrent overlay error correction in a first dimension between adjacent layers of the at least one wafer corresponding to a substantially similar overlay error correction in a second dimension between non-adjacent layers of the at least one wafer.